

ABSTRACT

A stamper with a sharp uneven pattern ~~is obtained, and~~ for manufacturing high precision information media can be manufactured using this stamper.

~~—A~~ and a method of manufacturing a stamper comprises the steps of stamper. The method includes (1) manufacturing a photoresist master 100-master by forming a light absorption layer 103-layer and a photoresist layer 104-layer on top of a substrate 102, substrate, (2) forming a latent image on the photoresist layer 104, layer, and then forming an uneven pattern 106-pattern in the photoresist layer 104-layer by developing the latent image, (3) forming a Ni thin film 108-film on the uneven pattern 106-pattern of the photoresist master 100-by electroless plating, (4) forming a Ni film 110-film on top of the Ni thin film 108,film, and (5) then-removing the Ni thin film 108-film and the Ni film 110-film from the photoresist master 100-master to form the stamper 120, wherein The method also includes, as preliminary treatments prior to the step of forming the Ni thin film 108-film on the photoresist layer 104, layer, a metal catalyst is-being provided on the surface of the uneven pattern 106, pattern, the metal catalyst is-being activated, and the surface of the uneven pattern 106-pattern on which the metal catalyst has been provided is-being washed with ultra pure water.